IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Takashi OZAKI, et al.

Serial Number: Not Yet Assigned

(§371 of International Application PCT/JP04/01996)

Filed: March 17, 2005

For: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR

MANUFACTURING A SEMICONDUCTOR DEVICE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

March 17, 2005

Sir:

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In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449 and cited in the enclosed international search report.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. <u>01-2340</u>.

Respectfully submitted,

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PATENT TRADEMARK OFFICE

Enclosures: PTO-1449; International Search Report

INFORMATION
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STATEMENT
PTO-1449

Atty. Docket No. 050161 Serial No. New Application

Applicant(s): Takashi OZAKI, et al.

Filing Date: March 17, 2005 Group Art Unit: Not Yet Assigned

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
	AA	·					
	AB						
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FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Translation (Yes or No)
	AE	2002-110562	04/12/02	Japan	Cited in the International Search Report
	AF	8-115883	05/07/96	Japan	Cited in the International Search Report
<u></u>	AG	2000-223432	08/11/00	Japan	Cited in the International Search Report
	AH	2002-280373	09/27/02	Japan	Cited in the International Search Report
	AI				

OTHER DOCUMENTS

	AJ	
	AK	
Examiner		Date Considered